



EV633261929

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 10/671,922  
Confirmation No. .... 8459  
Filing Date ..... September 24, 2003  
Inventor..... Garo J. Derderian et al.  
Assignee..... Micron Technology, Inc.  
Group Art Unit..... 2812  
Examiner ..... Lynne Ann Gurley  
Attorney's Docket No. .... MI22-2296  
Customer No. .... 021567  
Title: Atomic Layer Deposition Methods, and Methods of Forming Materials Over  
Semiconductor Substrates

**RESPONSE TO OCTOBER 18, 2005 FINAL OFFICE ACTION**

**Response to Accompany an RCE filing**

To: Mail Stop RCE  
Commissioner for Patents  
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**AMENDMENTS**